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**From:** Ira Matsil  
**Date:** July 12, 2004  
**Pages:** 4

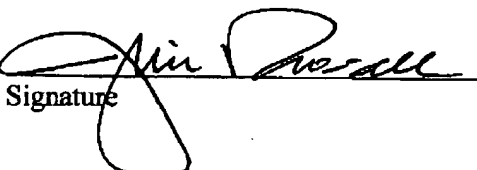
**Applicant:** Schulze, *et al.*  
**Serial No.:** 10/753,604  
**Filed:** January 8, 2004  
**Docket No:** 115747-0003/2002P50544US  
**Art Unit:** 1762  
**Examiner:** Unknown

**For:** Method for the Repair of Defects in Photolithographic Masks for Patterning  
Semiconductor Wafers

**Certificate of Transmission under 37 C.F.R. § 1.8**

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Request for Corrected Filing Receipt (1 page)  
Copy of Filing Receipt Marked to Show Changes (2 pages)

  
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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Schulze, *et al.* Docket No.: 115747-0003/2002P50544US  
Serial No.: 10/753,604 Art Unit: 1762  
Filed: January 8, 2004 Examiner: Unknown  
Title: Method for the Repair of Defects in Photolithographic Masks for Patterning  
Semiconductor Wafers

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**REQUEST FOR CORRECTION**

Sir:

Petitioner hereby requests a correction in the Filing Receipt of the above-referenced patent application. Enclosed is a copy of the Filing Receipt with the changes noted thereon.

Respectfully submitted,



July 12, 2004  
Date

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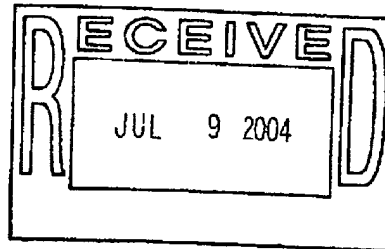
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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/753,604	01/08/2004	1762	1576	115747-0003//2002P50544US	3	48	5

25962  
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CONFIRMATION NO. 6349

## UPDATED FILING RECEIPT



\*OC000000013166866\*

Date Mailed: 07/07/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

Steffen F. Schulze, Sherwood, OR;  
Enio L. Carpi, Round Rock, TX;

Domestic Priority data as claimed by applicant

Foreign Applications

If Required, Foreign Filing License Granted: 04/19/2004

Projected Publication Date: 07/14/2005

Non-Publication Request: No

Early Publication Request: No

## Title

Method for the repair of defects in photolithographic masks for patterning semiconductor wafers

Preliminary Class

427

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Title 37, Code of Federal Regulations, 5.11 & 5.15**

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